

Notice of References Cited	Application/Control No. 10/751,360	Applicant(s)/Patent Under Reexamination PARK ET AL.	
	Examiner A. Dexter Tugbang	Art Unit 3729	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-3,350,180	10-1967	Croll	427/132 x
	B	US-5,283,942	02-1994	Chen et al.	29/603.15 x
	C	US-			
	D	US-			
	E	US-			
	F	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N	JP 64-47880	08-1997	Japan	Yamanaka et al	427/419.2 x
	O					
	P					
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	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Tomita et al., "Sputter-Deposited FeCoBC/AlN _x Multilayered Film for Wet-Etching Process", IEEE Transactions on Magnetics, Vol. 35, No. 5, Sept. 1999, pages 3571-3573.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.